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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In-re application of: Van Schravendijk, *et al.*

Attorney Docket No.:
NOVLP037C1/NVLS-000519C1

Application No.: 10/773,821

Examiner: DOLAN, JENNIFER M

Filed: February 5, 2004

Group: 2813

Title: APPLICATIONS AND METHODS OF
MAKING NITROGEN-FREE ANTI-
REFLECTIVE LAYERS FOR
SEMICONDUCTOR PROCESSING

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on November 16, 2005 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: _____

Tara Hayden

**INFORMATION DISCLOSURE STATEMENT
37 CFR §§1.56 AND 1.97(b)**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to examination of the above-identified patent application. Applicants submit the list of these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application. The above-identified application is a continuation in part of prior application U.S. Patent Application No. 11/168,013. This prior application is being relied upon for an earlier filing date under 35 U.S.C. § 120. Because the listed references were either cited by the PTO, or submitted to the PTO in the prior application, under 37 CFR § 1.98(d) Applicants submit that copies need not be provided.

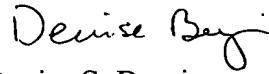
This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is: (i) filed within three (3) months of the filing date of the above-referenced application, (ii) believed to be filed before the mailing date of a first Office Action on the merits, or (iii) believed to be filed before the mailing of a first Office Action after the filing of a Request for Continued Examination under §1.114. Accordingly, it is

believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NOVLP037C1).

Respectfully submitted,

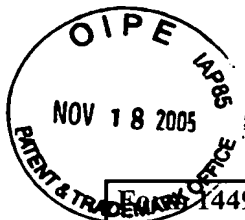
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Information Disclosure Statement By Applicant	EQA 1449 (Modified)	Atty Docket No. NOVLP037C1/NVLS-000519C1	Application No.: 10/773,821
		Applicant: van Schravendijk et al. Filing Date February 5, 2004	Group 2813

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	Li et al., "Methods of Forming Moisture Barrier for Low K Film Intergration with Anti-Reflective Layers", Novellus Systems, Inc., Appln. No. 11/168,013, filed June 27, 2005, pages 1-25. [NOVLP128/NVLS-3043]
	C2	U.S. Office Action mailed October 24, 2002, from U.S. Application No. 09/990,197. [NOVLP037/NVLS-000519]
	C3	U.S. Office Action mailed May 21, 2003, from U.S. Application No. 09/990,197. [NOVLP037/NVLS-000519]
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.